

## WEST Search History

09/ 816, 307

DATE: Monday, May 13, 2002

Set Name Query  
side by sideHit Count Set Name  
result set

DB=USPT,PGPB,JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ

L71	l67 and l2	5	L71
L70	L67 and l60	0	L70
L69	L67 and l19	0	L69
L68	L67 and l39	0	L68
L67	L66 and l5	24	L67
L66	portable with (leak near2 (detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3 or measur\$3))	207	L66
L65	L63 and l19	0	L65
L64	L63 and l7	2	L64
L63	l3 and l5	39	L63
L62	l60 and (l50 or l51)	0	L62
L61	L60 and l55	5	L61
L60	(seal\$4 near2 attach\$4) with wafer	56	L60
L59	L57 and l29	17	L59
L58	L57 and l19	0	L58
L57	L56 and l5	58	L57
L56	L55 and l7	289	L56
L55	(detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3 or measur\$3)with (contaminant or contaminat\$3)	42841	L55
L54	l5 and l9	0	L54
L53	l50 and l5	3	L53
L52	L51 and l5	4	L52
L51	((background or environment ) adj2 gas\$4) same (contamina\$4 near2 gas\$4)	82	L51
L50	((background or environment ) adj2 gas\$4) same (contaminant near2 gas\$4)	38	L50
L49	l19 and l21	4	L49
L48	L40 and l29	2	L48
L47	L44 and l20	0	L47
L46	L44 and l19	0	L46
L45	L44 and l119	0	L45
L44	L40 and l5	114	L44

L43	L41 and l29	0	L43
L42	L41 and l5	0	L42
L41	L40 and l7	8	L41
L40	L39 and compar\$4	1236	L40
L39	l11 and l12	2676	L39
L38	L37 and l19	0	L38
L37	l35 and l29	46	L37
L36	L35 and l21	0	L36
L35	l2 and l6	92	L35
L34	compar\$4 same (((background or environment ) adj2 gas\$4) same (contaminant near2 gas\$4))	1	L34
L33	L30 and (l1 or l2)	18	L33
L32	L30 and l11	1	L32
L31	L30 and l12	0	L31
L30	L29 and l7	81	L30
L29	((250/281  250/282  250/283  250/284  250/285  250/286  250/287  250/288  250/289  250/290  250/291  250/292  250/293  250/294  250/295  250/296  250/297  250/298  250/299  250/300 )!.CCLS. )	3743	L29
L28	l22 and l5	6	L28
L27	l7 and l21	3	L27
L26	l22 and l21	0	L26
L25	l24 and l22	2	L25
L24	5313061	23	L24
L23	L22 and l6	1	L23
L22	(l1 or l2) and l3	40	L22
L21	vacuum near2 t	586	L21
L20	(seal\$4 near2 attach\$4) with port	649	L20
L19	(seal\$4 near2 attach\$4) with (article or substrate or workpiece or semiconductor or surface)	4996	L19
L18	seal\$3 with (polymer near2 lining)	20	L18
L17	seal\$3 with polymer	23425	L17
L16	(seal\$4 or o-ring) near4 port	32104	L16
L15	ompar\$4 same (((background or environment ) adj2 gas\$4) with (contaminat\$3 near2 gas\$4))	0	L15
L14	(different\$6 or determin\$5 or difference) same (((background or environment ) adj2 gas\$4) with (contaminant near2 gas\$4))	2	L14
L13	compar\$4 same (((background or environment ) adj2 gas\$4) with (contaminant near2 gas\$4))	0	L13

L12	(contaminant or contaminat\$3) near4 (article or substrate or workpiece or semiconductor)	17157	L12
L11	(clean or standard or master) near4 (article or substrate or workpiece or semiconductor)	37453	L11
L10	l9 and ((detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3 or measur\$3)near4 gas\$4)	0	L10
L9	(outgas near4 contaminant)same (surface near2 (article or substrate or workpiece or semiconductor))	9	L9
L8	measur\$4 with (outgas near4 contaminant)	1	L8
L7	(detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3 or measur\$3)with ((environment or background)near3 gas\$4)	2402	L7
L6	(mass near2 (spectr\$6 or anal\$5)) with (environment or background)	514	L6
L5	(mass near2 (spectr\$6 or anal\$5))	53858	L5
L4	pump near4 (evacuat\$3 or vacuum)	88182	L4
L3	portable same ((housing or chamber or bell or enclosure) near4 (evacuat\$3 or vacuum))	632	L3
L2	(detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3) with (contaminant or contamina\$4)	37569	L2
L1	(detect\$3 or monitor\$3 or anal\$5 or draw\$3 or test\$3) with (outgas near4 contaminant)	3	L1

END OF SEARCH HISTORY